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(54) Title: GAS SHIELDING DEVICE FOR USE WITH A LASER PROCESSING HEAD

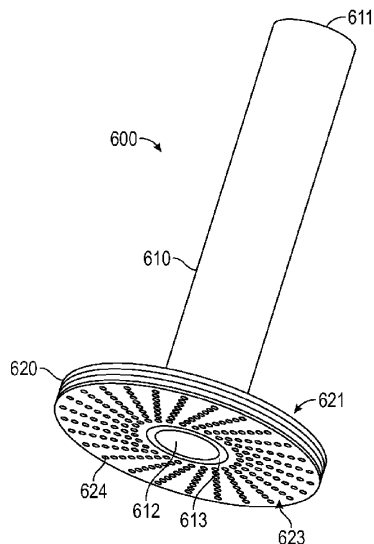


FIG. 6

(57) Abstract: A gas shielding device may be used with a laser processing head, such as a welding head, to diffuse and distribute a shield gas over a larger gas shielding area for shielding a larger area of metal. The gas shielding device may be coupled to the laser processing head to move with the laser beam and may be arranged coaxially to provide the larger shielding effect in all directions of welding. The gas shielding device is particularly useful for welding titanium or other metals that are highly reactive with gases in the air and/or for larger welding areas (e.g., where the laser beam is wobbled).

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